

Applicant: Ryo NAKAGAKI, et al.

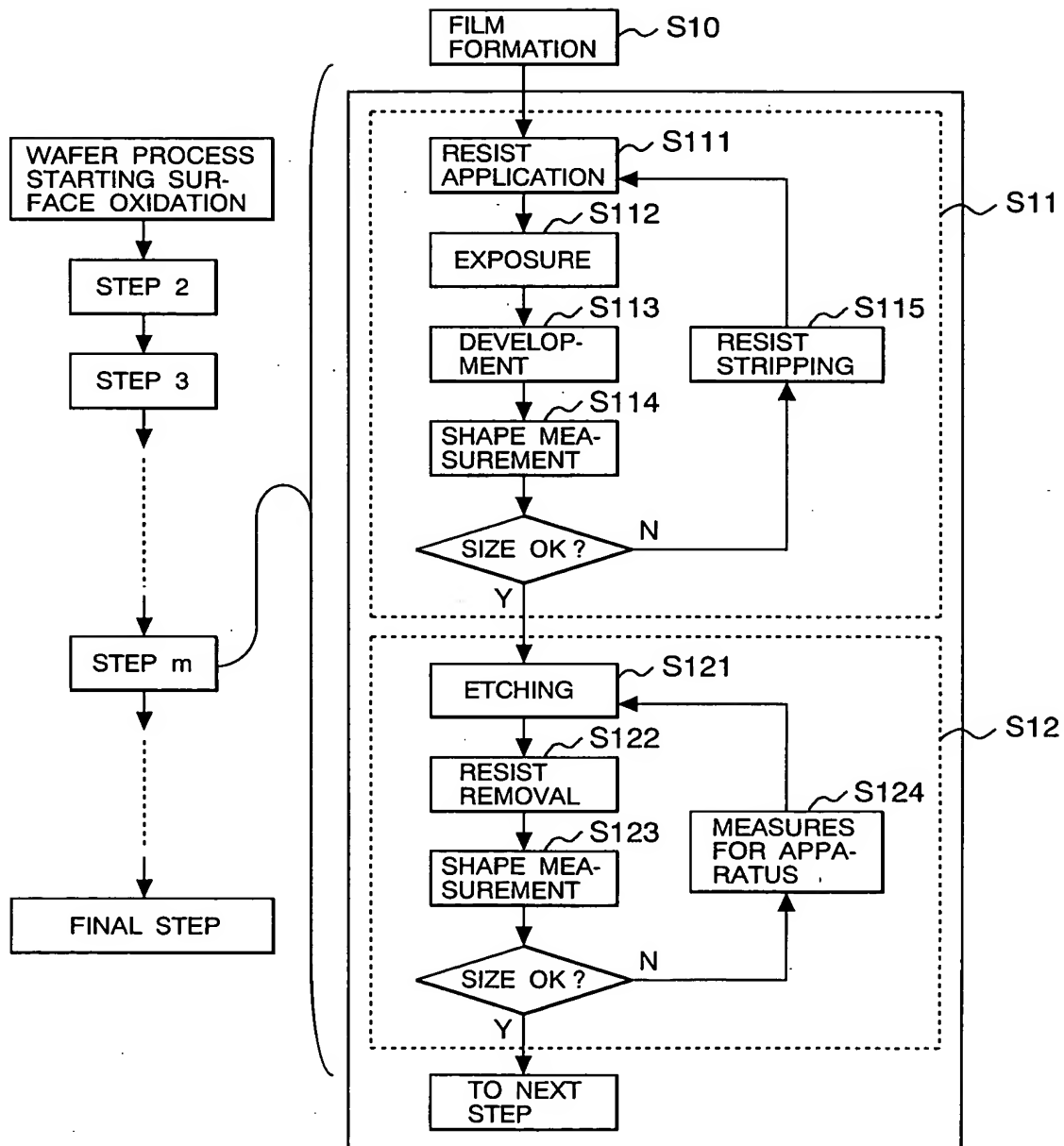
Title: Method and System for Manufacturing Semiconductor Device

Atty Dock t N . 16869N-099100US

Sheet 1 of 21

1/21

FIG. 1



Applicant: Ryo NAKAGAKI, et al.

Title: Method and System for Manufacturing Semiconductor Device

Attorney No. 16869N-099100US

Sheet 2 of 21

2/21

FIG. 2A

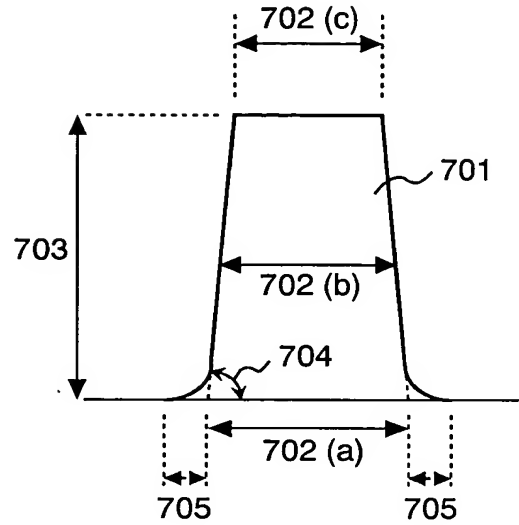
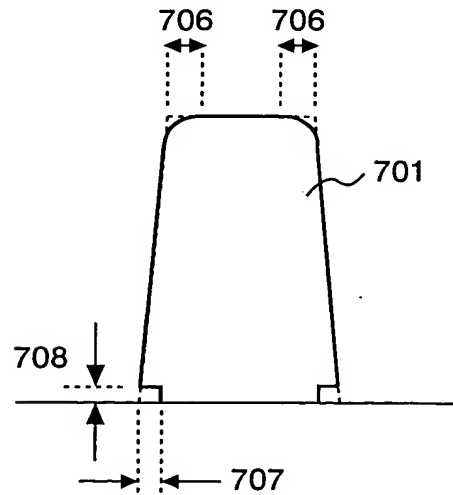


FIG. 2B



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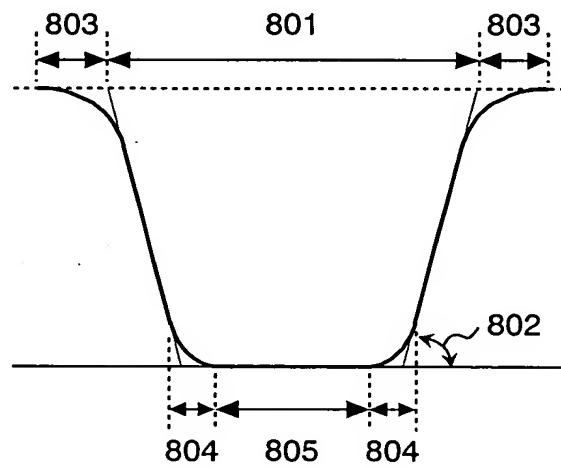
Title: Method and System for Manufacturing Semiconductor Device

Attorney No. 16869N-099100US

Sheet 3 of 21

3/21

FIG. 3



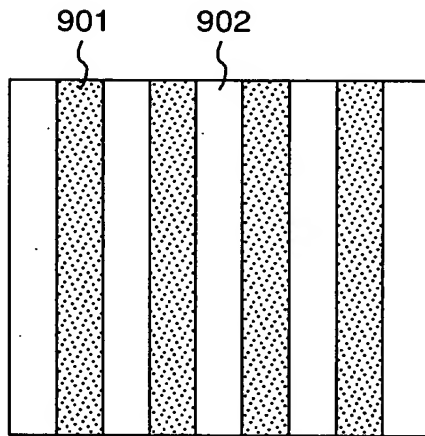
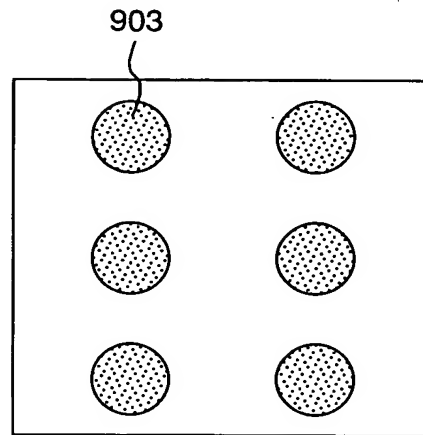
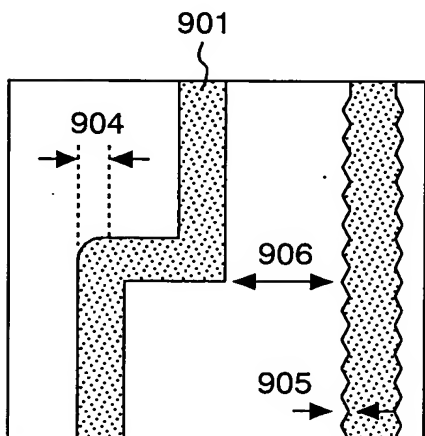
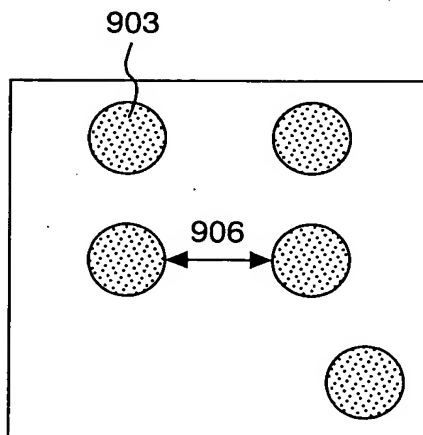
Applicant: Ryo NAKAGAKI, et al.

Title: Method and System for Manufacturing Semiconductor Device

Atty Dock t N . 16869N-099100US

She t 4 f 21

4/21

FIG. 4A**FIG. 4B****FIG. 4C****FIG. 4D**

Applicant: Ryo NAKAGAKI, et al.

Title: Method and System for Manufacturing Semiconductor Device

Attorney No. 16869N-099100US

Sheet 5 of 21

5/21

FIG. 5A

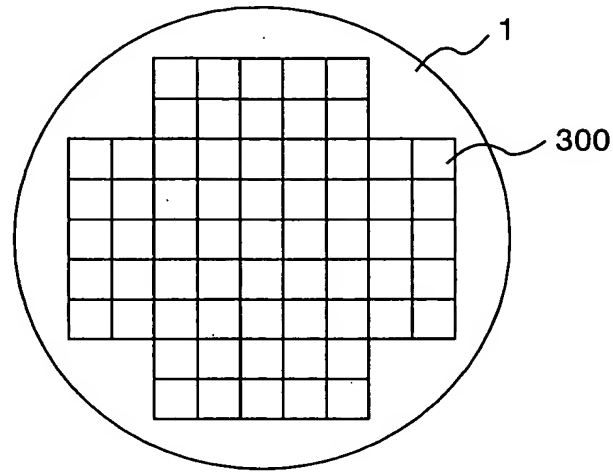


FIG. 5B

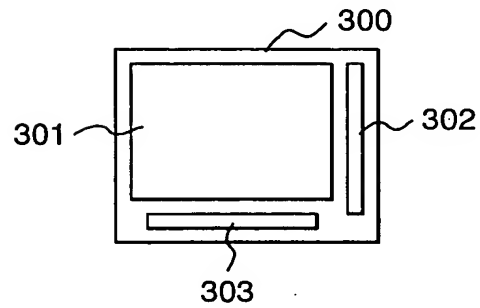
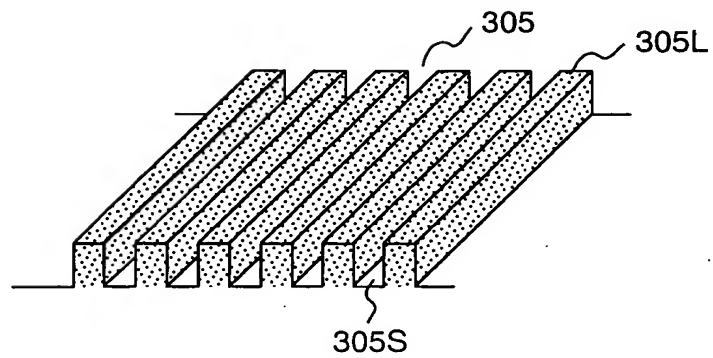


FIG. 6



6/21

FIG. 7

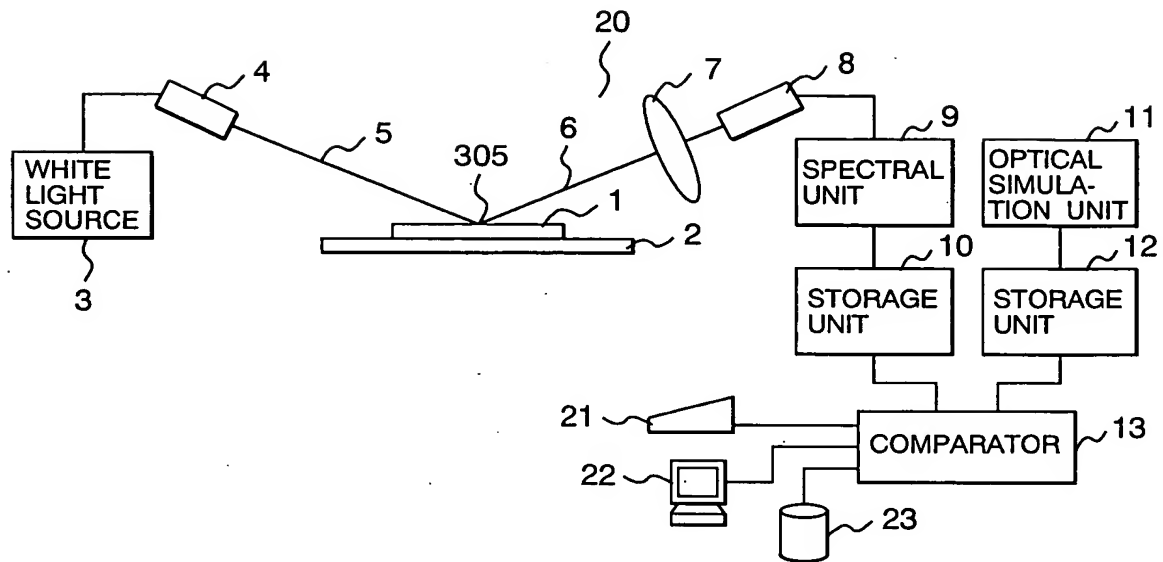
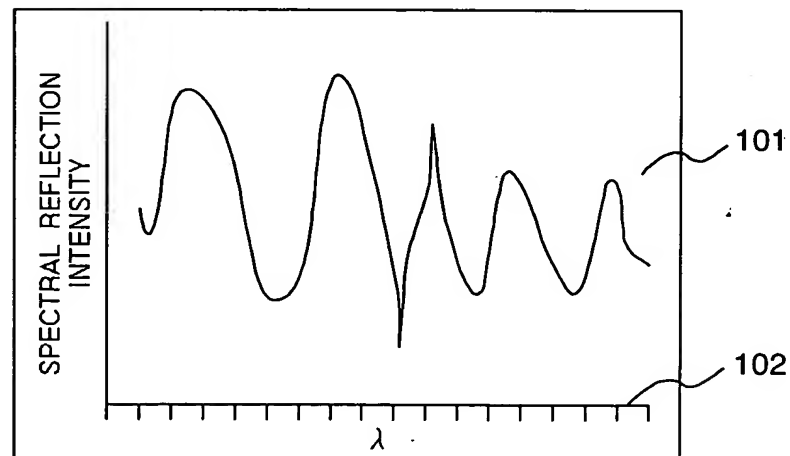


FIG. 8



7/21

FIG. 9

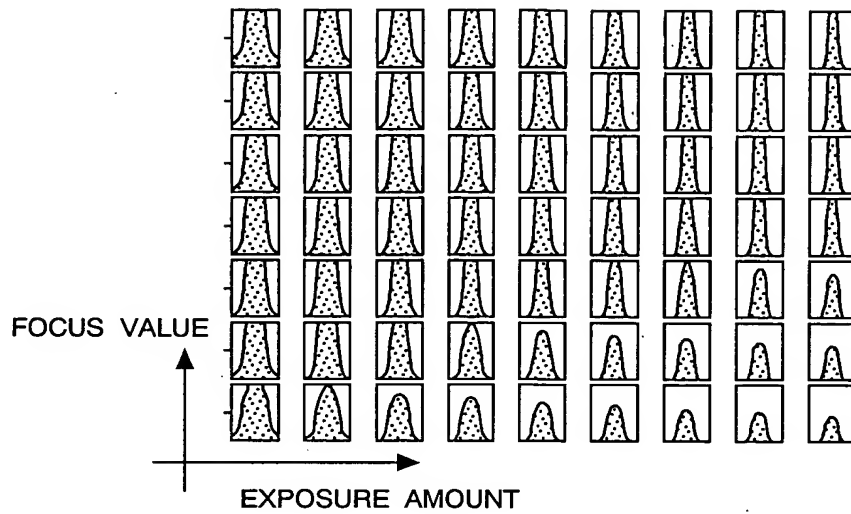


FIG. 10A

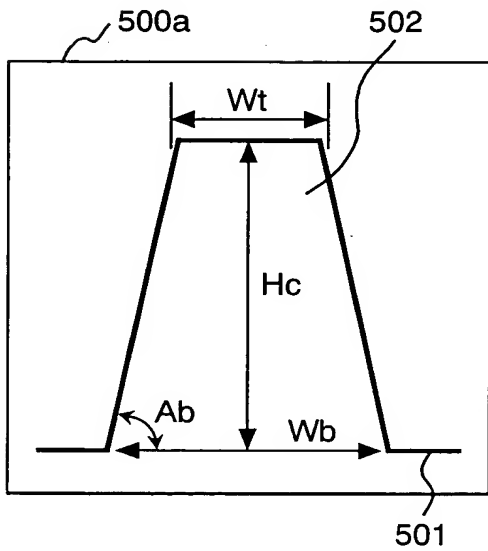
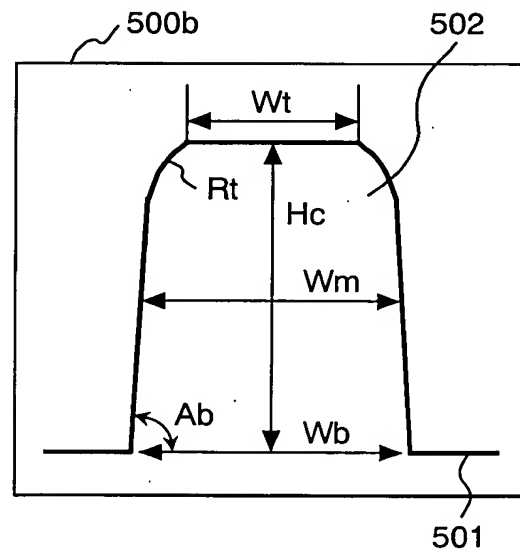


FIG. 10B



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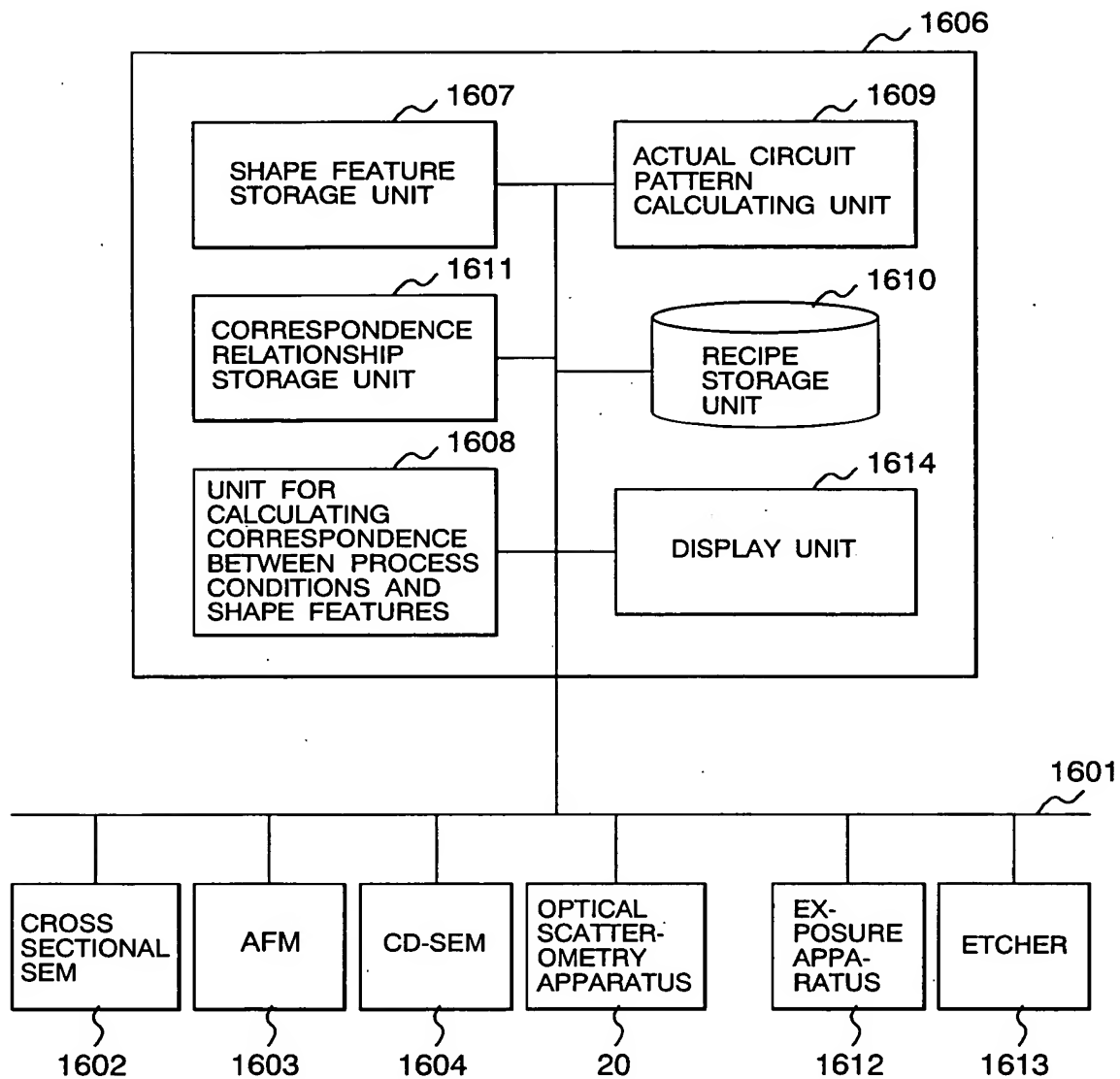
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Atty D cket N . 16869N-099100US

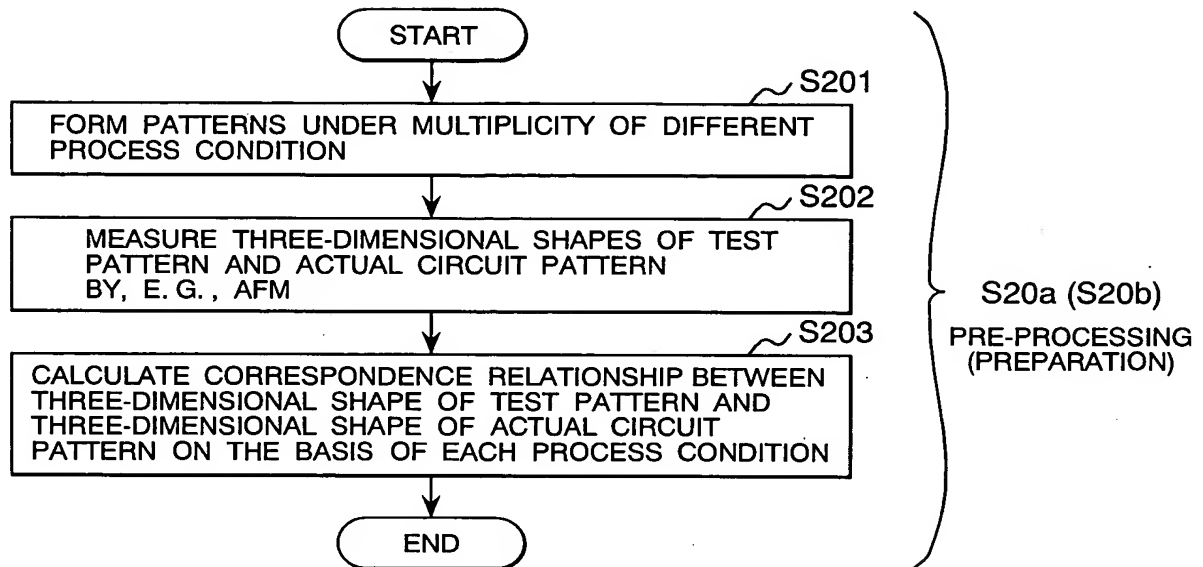
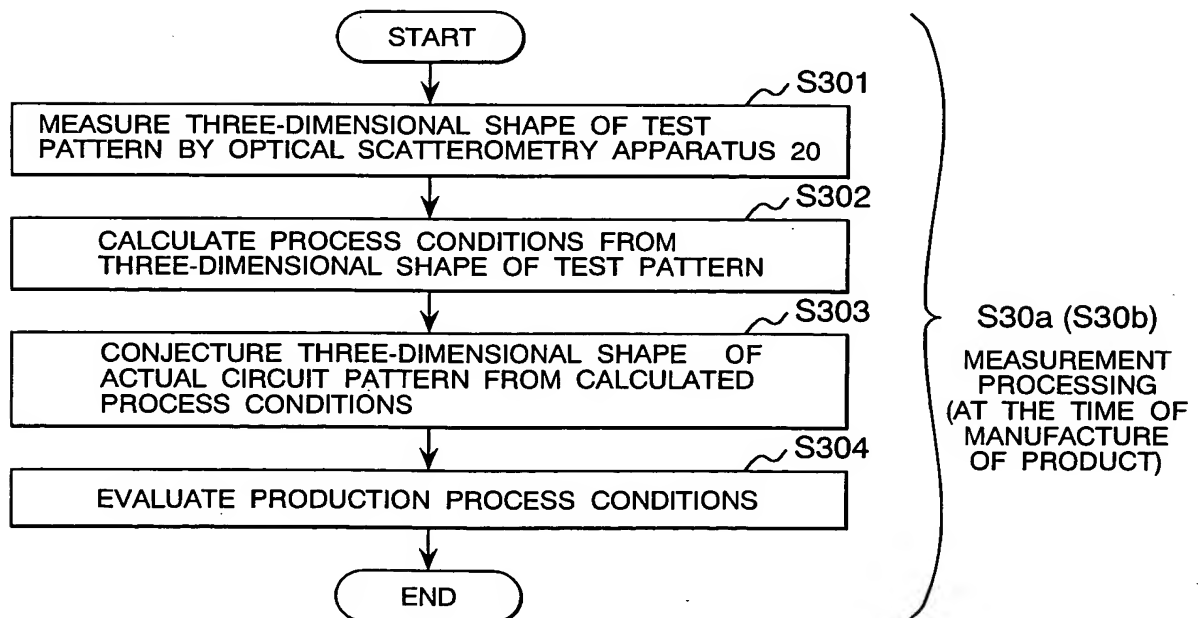
Sheet 8 of 21

8/21

FIG. 11



9/21

FIG. 12A**FIG. 12B**

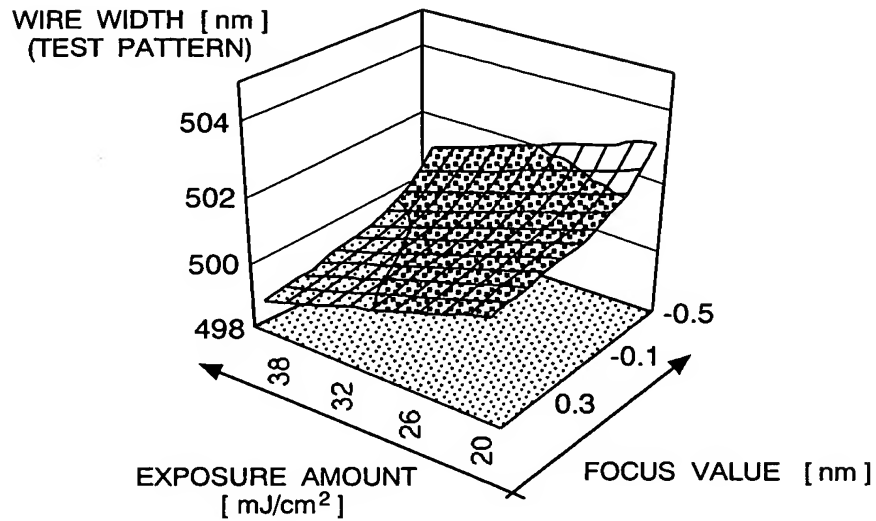
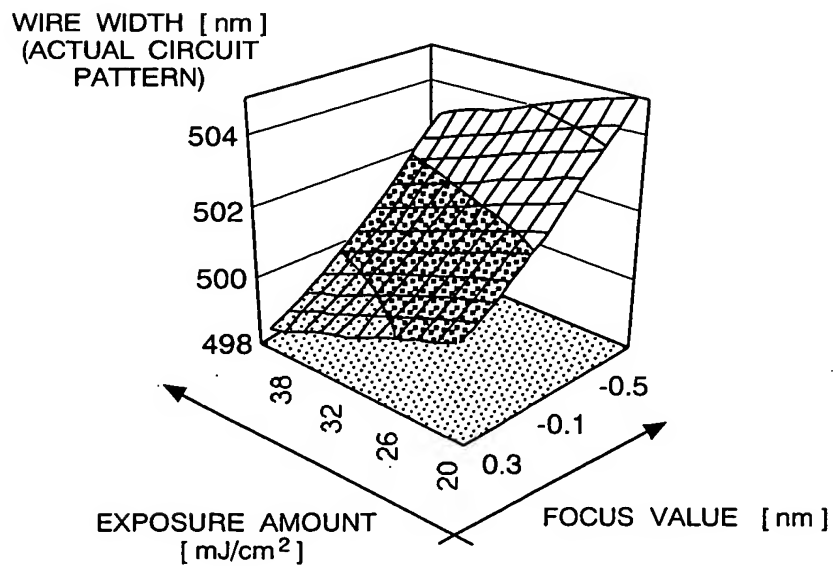
Applicant: Ryo NAKAGAKI, et al.

Title: Method and System for Manufacturing Semiconductor Device

Atty Docket No. 16869N-099100US

Sheet 10 of 21

10/21

FIG. 13A**FIG. 13B**

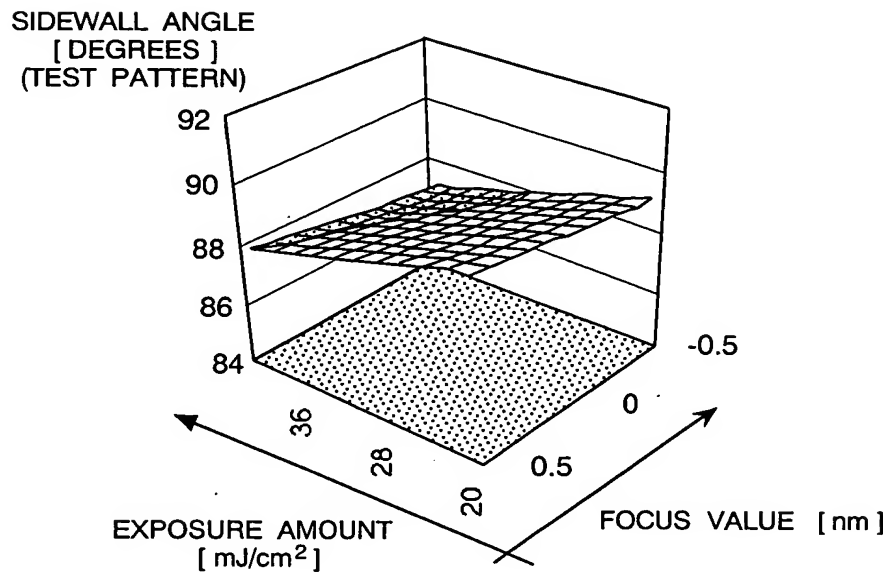
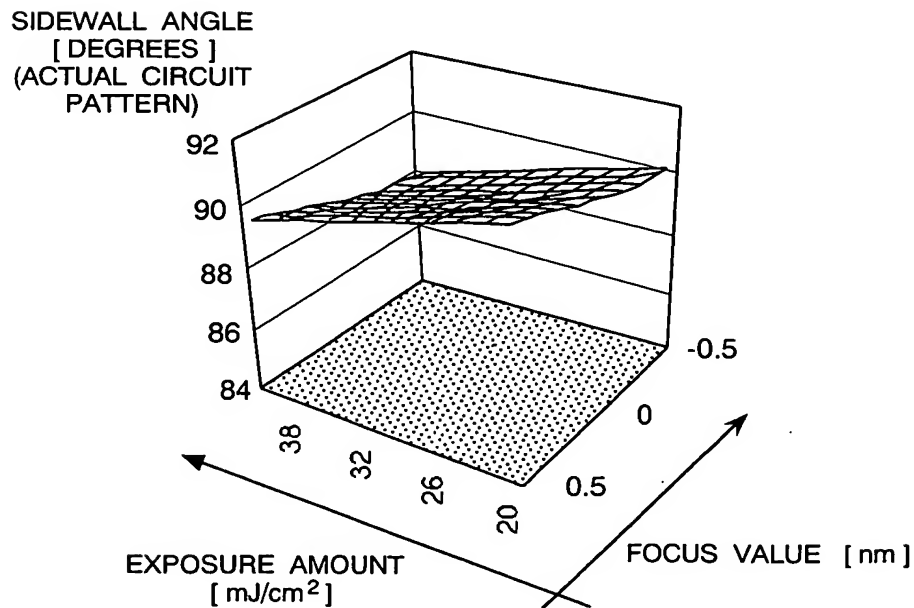
Applicant: Ryo NAKAGAKI, et al.

Title: Method and System for Manufacturing Semiconductor Device

Atty Dock t No. 16869N-099100US

Sheet 11 of 21

11/21

FIG. 14A**FIG. 14B**

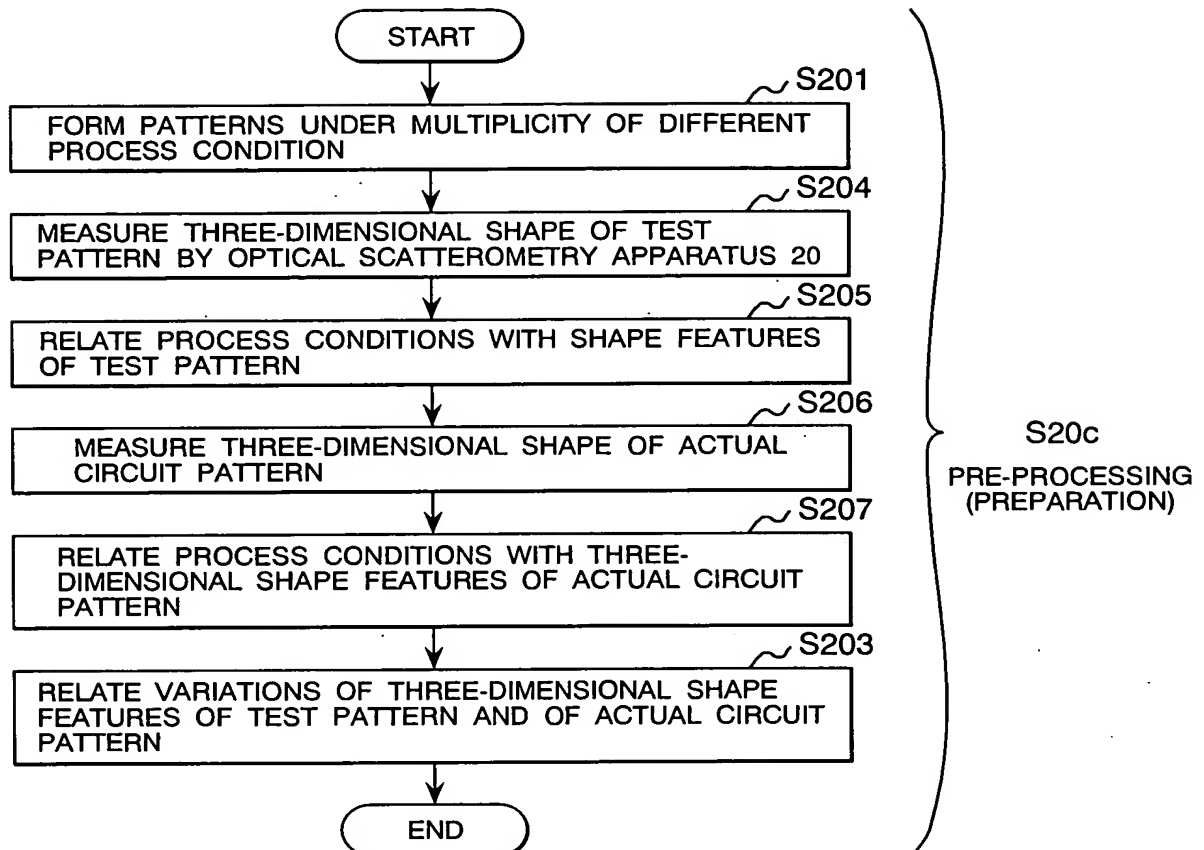
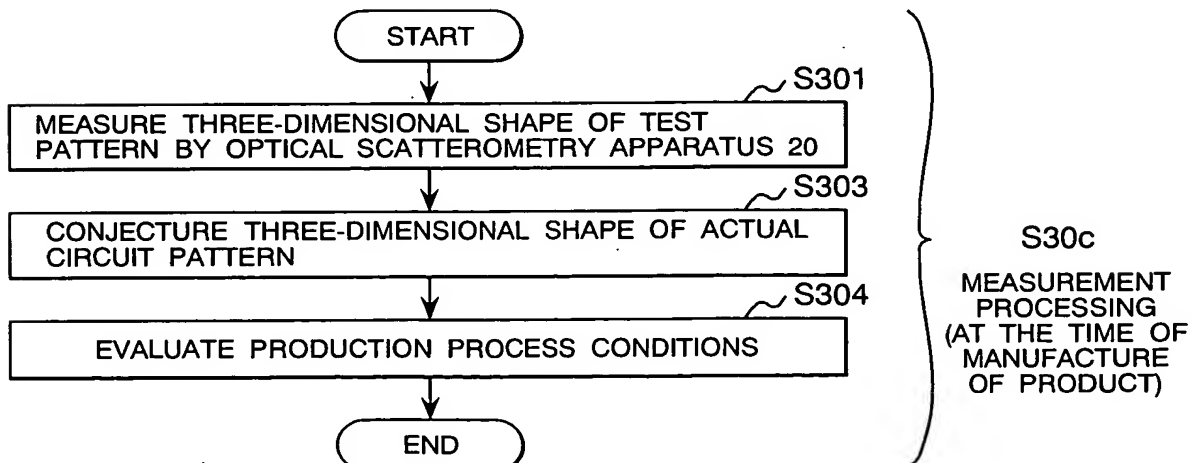
Applicant: Ryo NAKAGAKI, et al.

Title: Method and System for Manufacturing Semiconductor Device

Atty Docket No. 16869N-099100US

Sheet 12 of 21

12/21

FIG. 15A**FIG. 15B**

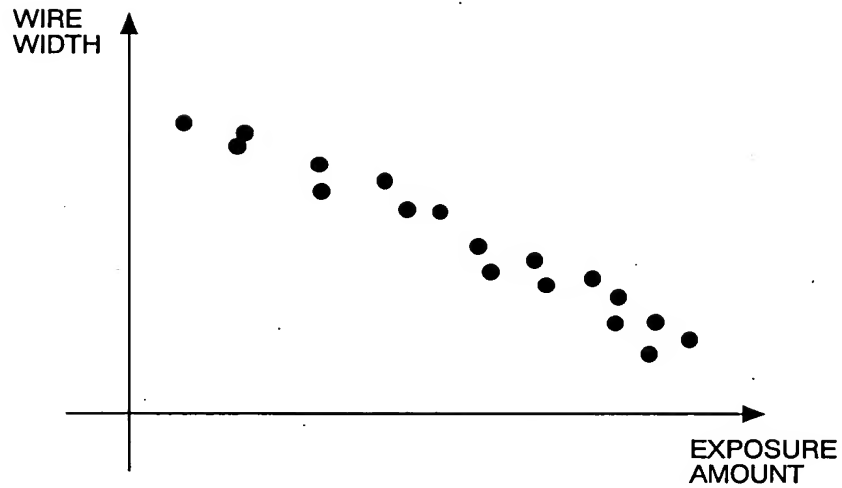
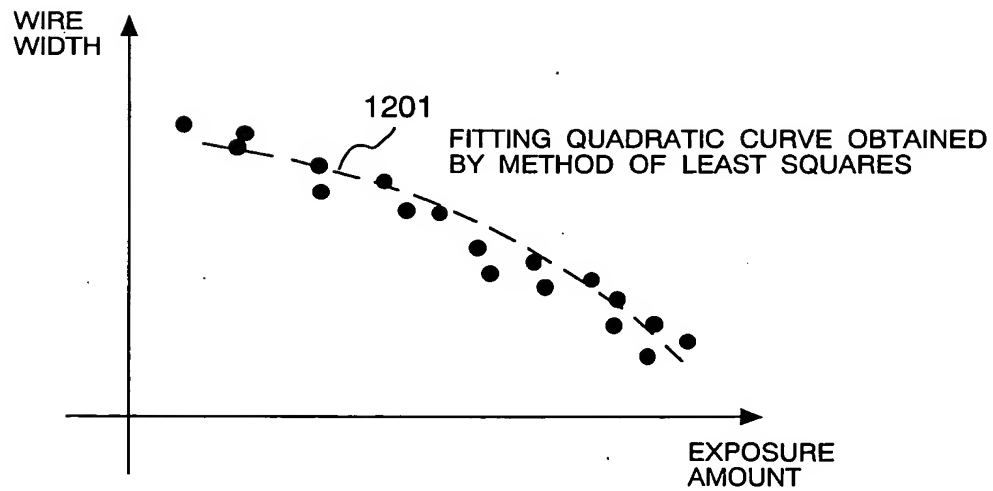
Applicant: Ryo NAKAGAKI, et al.

Title: Method and System for Manufacturing Semiconductor Device

Atty D cket N . 16869N-099100US

Sh et 13 of 21

13/21

FIG. 16**FIG. 17**

Applicant: Ryo NAKAGAKI, et al.

Title: Method and System for Manufacturing Semiconductor Device

Atty Docket No. 16869N-099100US

Sh et 14 f 21

14/21

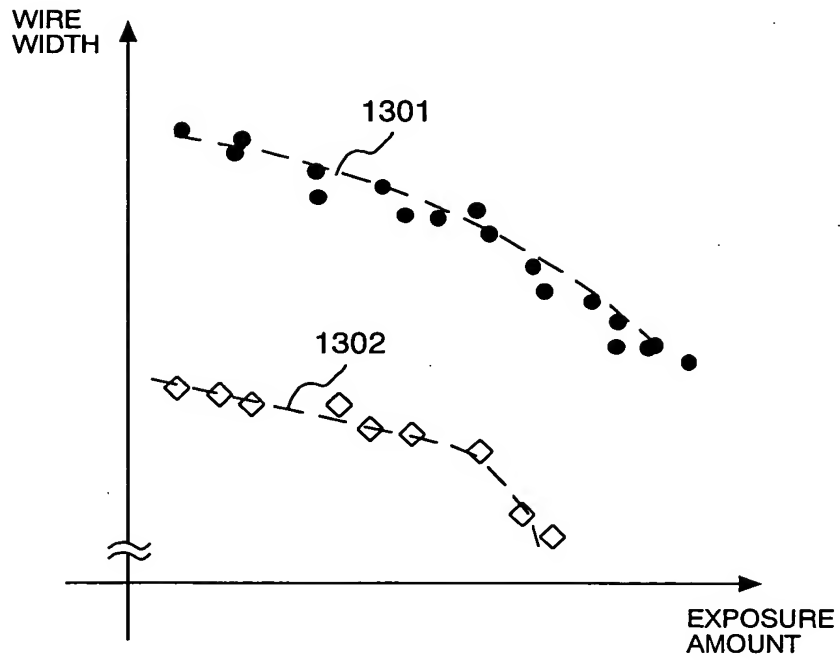
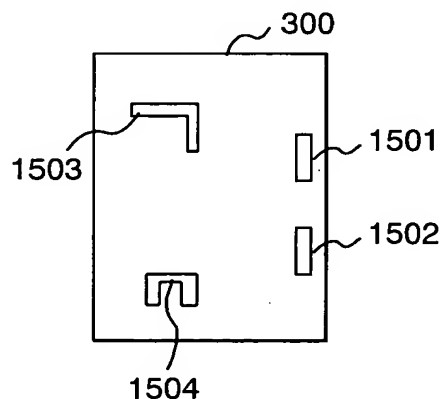
FIG. 18

FIG. 19

#	TEST PATTERN	CRITICAL ACTUAL CIRCUIT PATTERN
1	PATTERN A WIRE WIDTH = F1a (CONDITION1, CONDITION2) SIDEWALL ANGLE = F2a (CONDITION1, CONDITION2)	PATTERN C WIRE WIDTH = F1c (CONDITION1, CONDITION2) SIDEWALL ANGLE = F2c (CONDITION1, CONDITION2)
2	PATTERN B WIRE WIDTH = F1b (CONDITION1, CONDITION2) SIDEWALL ANGLE = F2b (CONDITION1, CONDITION2)	PATTERN D WIRE WIDTH = F1d (CONDITION1, CONDITION2) SIDEWALL ANGLE = F2d (CONDITION1, CONDITION2)

FIG. 20



Applicant: Ryo NAKAGAKI, et al.

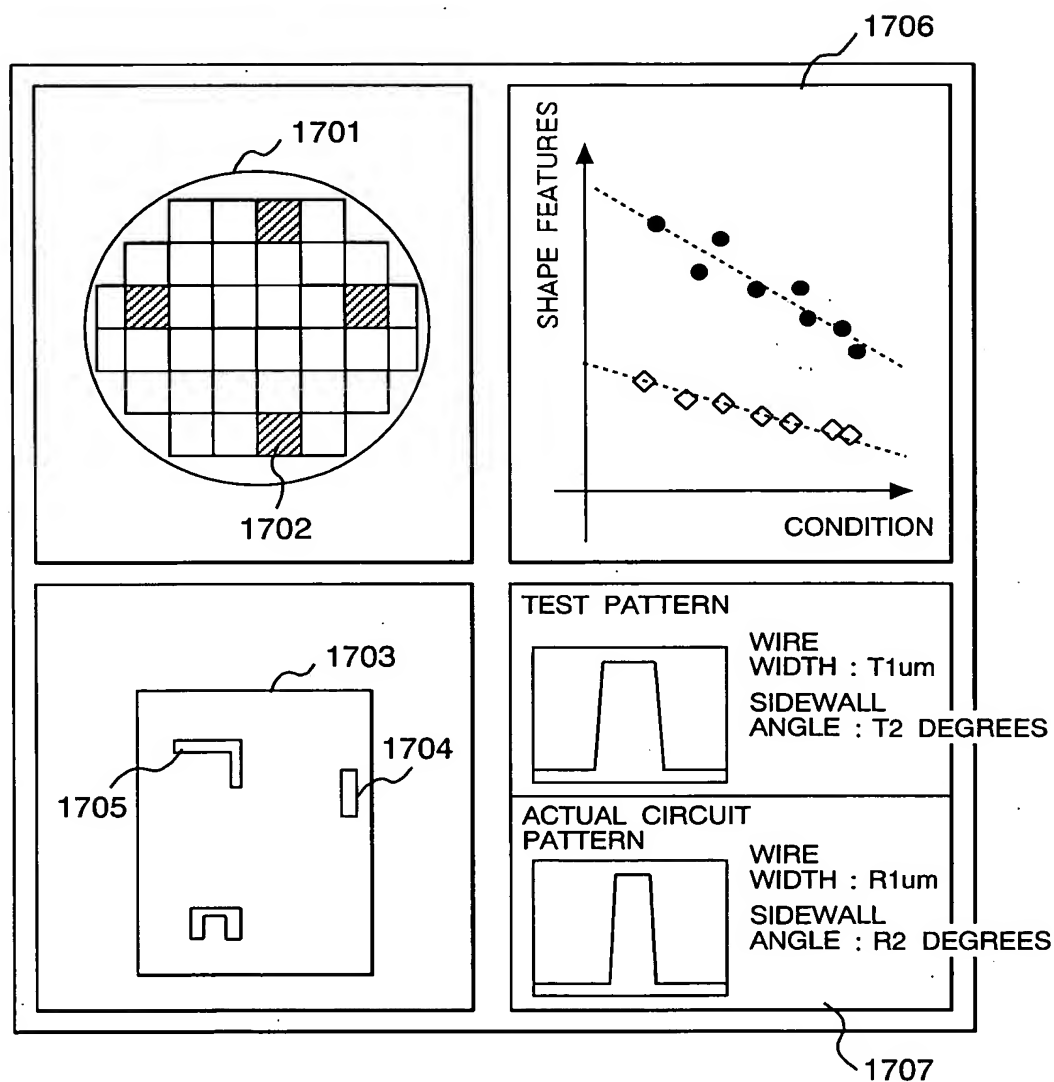
Title: Method and System for Manufacturing Semiconductor Device

Atty Docket No. 16869N-099100US

Sheet 16 of 21

16/21

FIG. 21



Applicant: Ryo NAKAGAKI, et al.

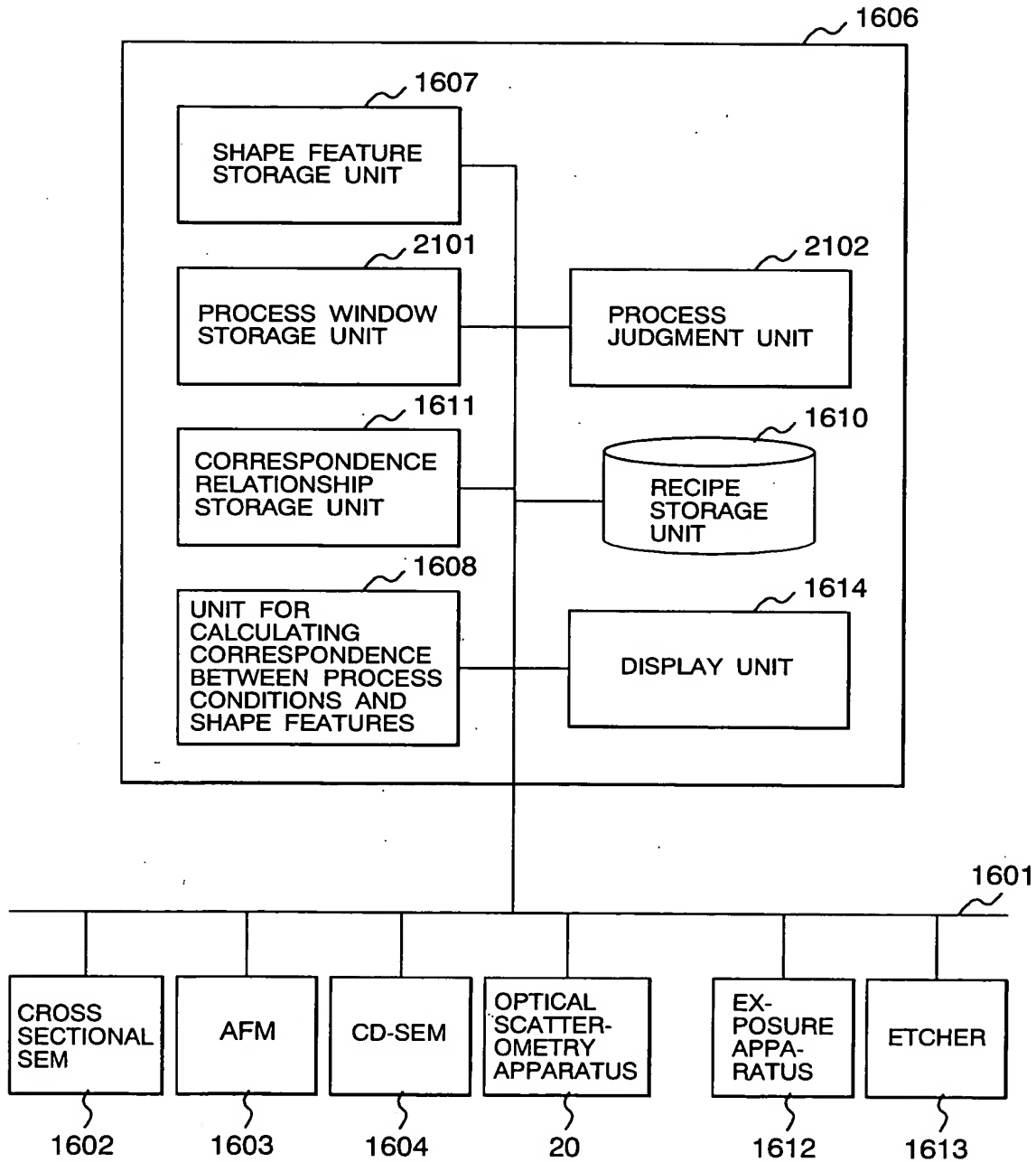
Title: Method and System for Manufacturing Semiconductor Device

Attorney No. 16869N-099100US

Sheet 17 of 21

17/21

FIG. 22



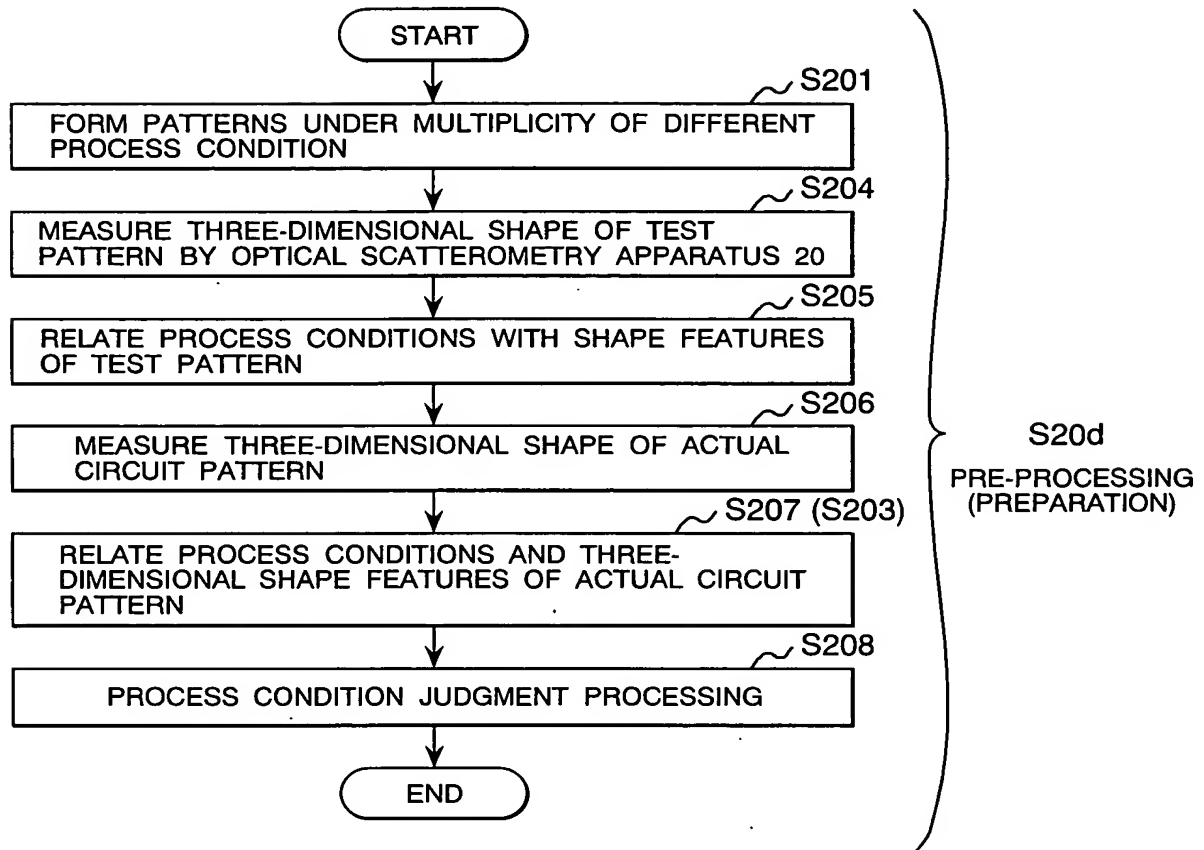
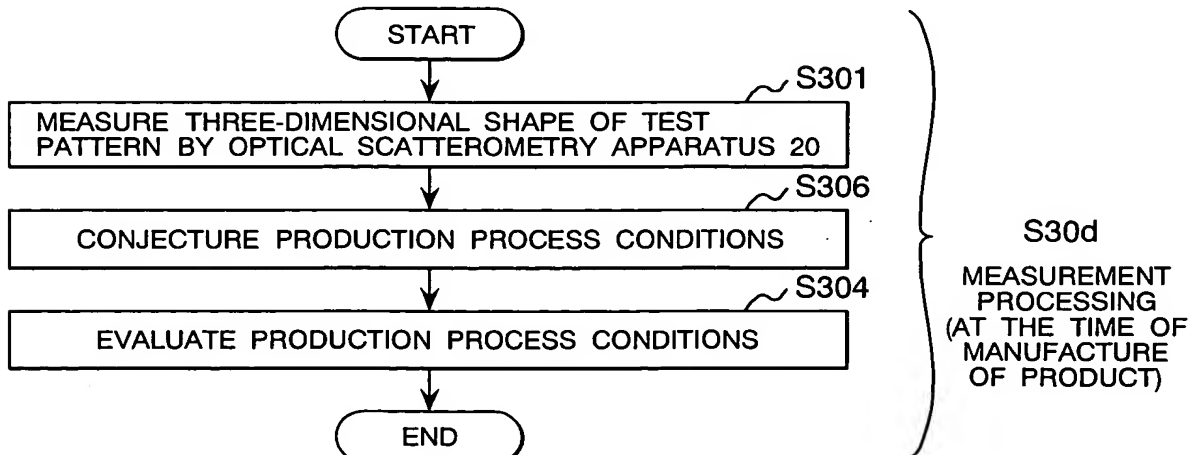
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Title: Method and System for Manufacturing Semiconductor Device

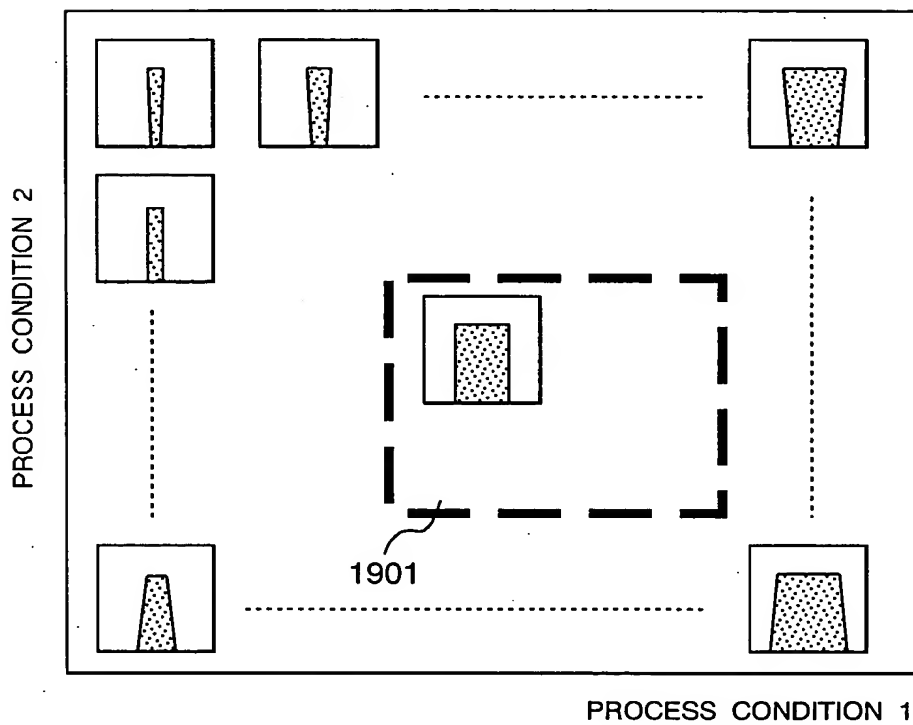
Atty Docket N . 16869N-099100US

Sh et 18 of 21

18/21

FIG. 23A**FIG. 23B**

19/21

FIG. 24

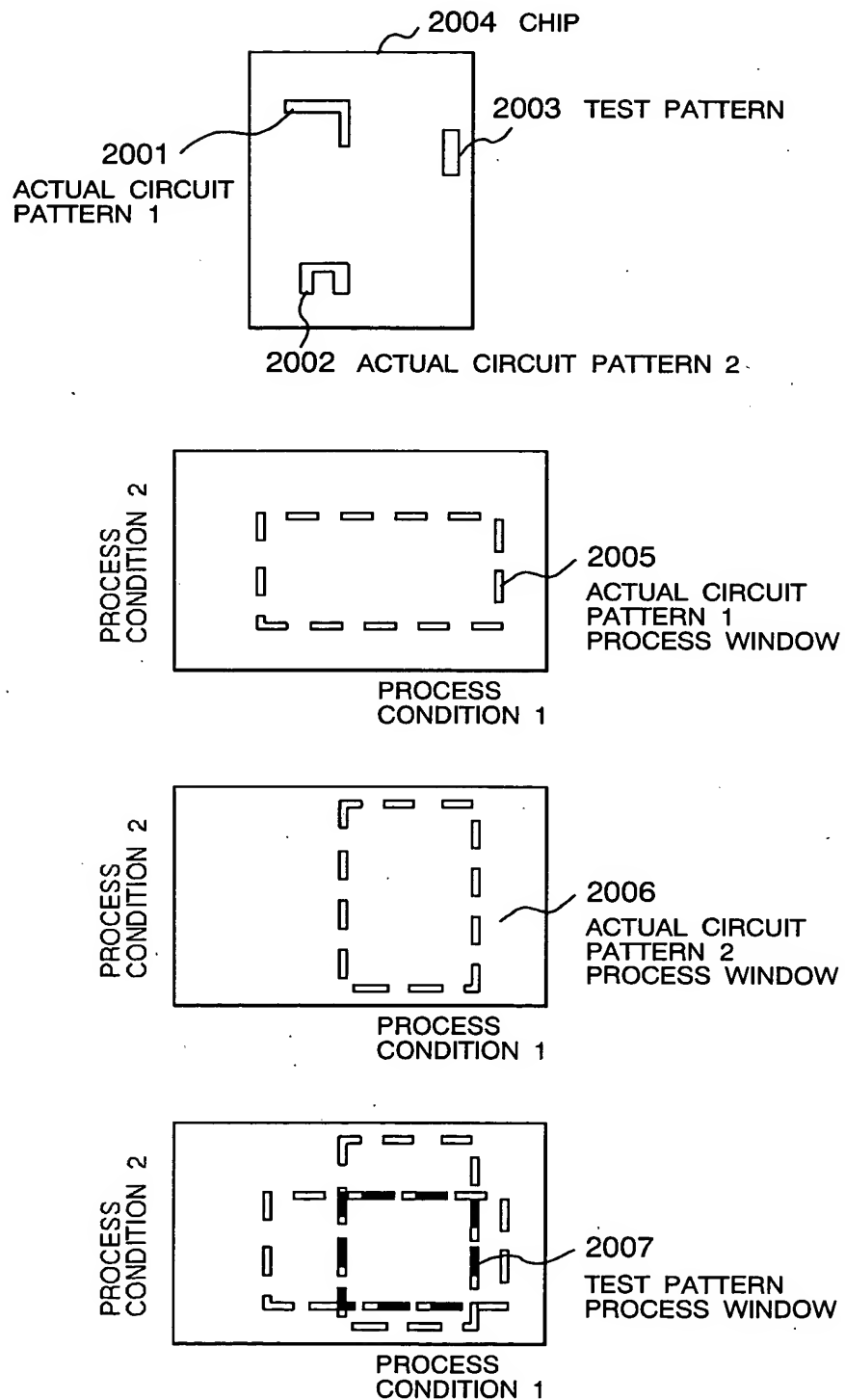
Applicant: Ryo NAKAGAKI, et al.

Title: Method and System for Manufacturing Semiconductor Device

Atty Dock t No. 16869N-099100US

Sheet 20 of 21

20/21

FIG. 25

Applicant: Ryo NAKAGAKI, et al.

Title: Method and System for Manufacturing Semiconductor Device

Atty Dock t N . 16869N-099100US

Sheet 21 of 21

21/21

FIG. 26

